



Evactron®

By XEI Scientific

Evactron® U50 Plasma De-Contaminator

With Wired Touchpad Control

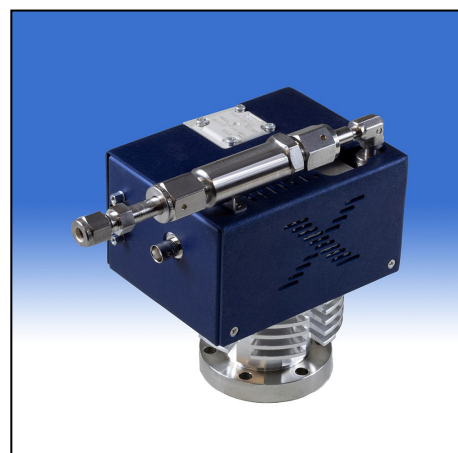
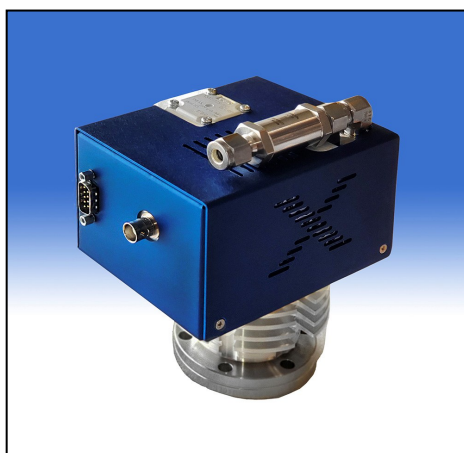
UHV VACUUM CHAMBER CLEANING SYSTEM

The Evactron U50 De-Contaminator is a compact, high performance yet simplified plasma cleaner for instruments and chambers designed to operate at UHV conditions. The U50 delivers high power cleaning for removal of hydrocarbon contamination on chamber and sample surfaces.

The compact design of the Evactron U50 Plasma Radical Source (PRS) makes it a versatile solution for either instrument chambers, load locks, or sample prep chambers. The Evactron U50 offers fast, effective, and powerful cleaning over a wide range of pressures, enabling hydrocarbon-free RGA spectra and fast pumpdown time to UHV.

System Features:

- RF Power: 75W peak, up to 50W continuous
- Dual action cleaning using plasma and UV afterglow
- Energy efficient radio frequency hollow cathode plasma (RFHC)
- Conflat 2.75 flange for UHV compatibility
- Programmable power, cleaning time, number of cycles, recipes
- Tethered touchpad command communications module
- Wide range pressure operation: 0.3 Pa/ 2 mTorr to 80 Pa/ 600 mTorr
- Bakeable to 150°C and nitrogen purge mode for optimal cleaning
- TMP compatible, no advance venting needed
- Fast cleaning, 100X+ faster than earlier generation Evactron models
- Non-damaging to sensitive components - no sputter etch
- Leak tested to $<10^{-11}$ Torr or 10^{-11} mBar ($1.3E-9$ Pa)
- Push button cleaning operation
- No match or gas flow adjustments needed for plasma ignition
- TUV, NRTL, SEMI, CE and RoHS compliant



Evactron® U50 Plasma Cleaner with standard (left) and ultrafilter (right)

www.evactron.com

+1.650.369.0133

sales@evactron.com

Remote Plasma Cleaner

Evactron U50 Specifications



The **Evactron U50 Plasma De-Contaminator** was designed for facilities that prefer a wired touchpad interface for programming cleaning parameters. The touchpad (134x112x69mm) is connected by a RS-232 cable to the controller. The simplified PRS has a small footprint and utilizes air or alternate gas plasma and UV afterglow to reduce hydrocarbon contamination, delivering results quickly.

Evactron U50 System Specifications:

- Evactron U50 plasma radical source
- Desktop controller with pushbutton operation
- Tethered touchpad communication package
- Hardware interlock
- Chassis dimensions: W×H×D: 17.2"×3.5"×8.6" (44×8.9×22 cm)
- RF Power: 35 - 75 Watts at 13.56 MHz RFHC
- 100-240 VAC 50/60 Hz input
- RoHS Compliant



Global Headquarters

1755 East Bayshore Road, Suite 17
Redwood City, CA 94063

Office: 650.369.0133/ 800.500.0133

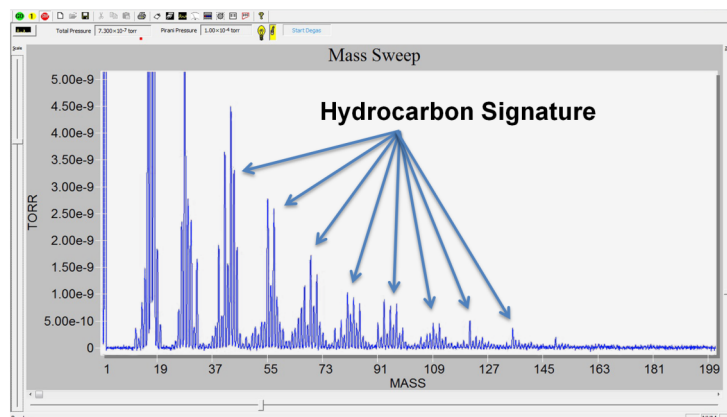
Fax: 650.363.1659

Web: www.evactron.com

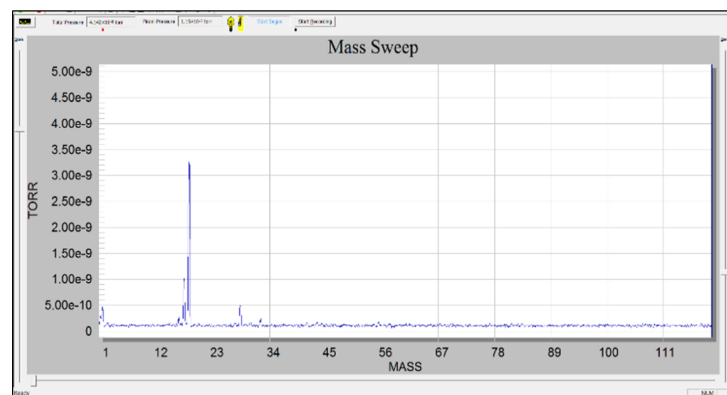
Contact: sales@evactron.com



RGA Before Evactron Cleaning



RGA After Evactron Cleaning



Residual Gas Analyzers (RGA) are powerful tools used to measure and identify gases and contaminants in vacuum chambers. The new Evactron U50 plasma cleaner operates from a lower base pressure compared to previous models and rapidly removes most hydrocarbons from a vacuum chamber. RGA spectra can be taken soon after the plasma is stopped so that hydrocarbons can be monitored before being changed by migration.